

IN THE SPECIFICATION:

Please enter the changes in the specification indicated below:

At the paragraph bridging pages 5-6:

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Figure 3 shows a cross-section of a coplanar chuck 9 [10] where deposition electrodes 4 [14] are separated from shield electrodes 3 [13] by dielectric (preferably atmosphere) 5 [15], with these features seated in base material 2 [12]. The deposition electrodes 4 [14] are preferably formed of series 300 stainless steel. Deposition electrodes 4 [14] contain a pin receptacle 6 [16] for connection to circuit board 1 [11]. Base material 2 [12] is made of a dielectric such as Noryl® polymer (GE Plastics, Pittsfield, MA). Noryl engineered plastics are modified polyphenylene oxide, or polyphenylene oxide and polyphenylene ether, resins. The modification of these resins involves blending with a second polymer such as polystyrene or polystyrene/butadiene. By varying the blend ratio and other additives, a variety of grades are produced. Unmodified, these polymers are characterized by regular closely spaced ring structures (phenyl groups) in the main molecular chain. This feature along with strong intermolecular attraction causes extreme stiffness and lack of mobility. The shield electrodes 3 [13] can be made from a conductive material (such as 300 series stainless steel) adhered to the base material 2 [12], for example by an adhesive or a double-sided, rubber-based adhesive tape. The annular gaps that are the preferred embodiment of dielectric 5 [15] can be made by drilling a series of holes in the conductor layer that will form the shield electrodes 3 [13]. The deposition electrodes 4 [14] can be, for example, pressed or glued into the base material. The assembly is preferably ground to create a flat, coplanar surface, for example within a tolerance of 0.0002 inches. Where dielectric 5 [15] is atmosphere (that atmosphere in which the electrostatic chuck operates), preferably the portion of the dielectric separation of the electrodes comprising atmosphere is sufficient so that in use the upper plane of the electrostatic chuck aligned with dielectric 5 [15] discharges completely between depositions. Such an amount of dielectric separation is “substantial” separation.

At the paragraph bridging pages 7-8:

The invention described herein can be used in conjunction with a number of devices and methods described by applicants or those working with applicants. For example, the "Electrostatic Sensing Chuck Using Area Matched Electrodes" [application] patent of Sun et al., [Serial] No. 6,370,005 [09/417,736, filed October 14, 1999], and the "Device for the Dispersal and Charging of Fluidized Powder" [application] patent of Sun et al., [Serial] No. 6,491,241 [09/417,820, October 14, 1999] can be used in conjunction with the invention. Other devices or methods that can be used with various aspects of the present invention include, for example, the methods for use of transporter chucks, acoustic bead dispensers and other powder-manipulating devices set forth in Sun, "Chucks and Methods for Positioning Multiple Objects on a Substrate," US Patent No. 5,788,814, issued August 4, 1998; Sun et al., "Electrostatic Chucks and a Particle Deposition Apparatus Therefor," US Patent No. 5,858,099, issued January 12, 1999; Pletcher et al., "Apparatus for Electrostatically Depositing a Medicament Powder Upon Predefined Regions of a Substrate," US Patent No. 5,714,007, issued February 3, 1998 (see, also US Patent No. 6,007,630, issued December 28, 1999); Sun et al., "Method of Making Pharmaceutical Using Electrostatic Chuck," US Patent No. 5,846,595, issued December 8, 1998; Sun et al., "Acoustic Dispenser," US Patent No. 5,753,302, issued May 19, 1998; Sun, "Bead Transporter Chucks Using Repulsive Field Guidance," US Patent 6,098,368, issued 1-Aug-2000; Sun, "Bead Manipulating Chucks with Bead Size Selector," US Patent No. 5,988,432, issued November 23, 1999; Sun, "Focused Acoustic Bead Charger/Dispenser for Bead Manipulating Chucks," US Patent 6,168,666, issued 2-Jan-2001; Sun et al., "AC Waveforms Biasing For Bead Manipulating Chucks," US Patent 6,149,774, issued 21-Nov-2000.; Sun et al, "Method [Apparatus] for Clamping a Planar Substrate," [Serial] No. 6,399,143 [09/095,321, filed 10 June 1998]; Poliniak et al., "Dry Powder Deposition Apparatus," US Patent 6,063,194, issued 16-May-2000; and "Pharmaceutical Product [and Method of Making]," [Serial] No. 6,303,143 [09/095,616, filed 10 June 1998]. Additional powder-handling devices, including a cone-shaped cloud chamber, are

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described in O'Mara et al., "Article Comprising a Diffuser with Flow Control Features," [Serial] No. 6,444,033 [09/438,801, filed 12-Nov-1999].
